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(54) **Title:** APPARUSES FOR UNIFORM FLUID DELIVERY IN A MULTI-STATION SEMICONDUCTOR PROCESSING CHAMBER

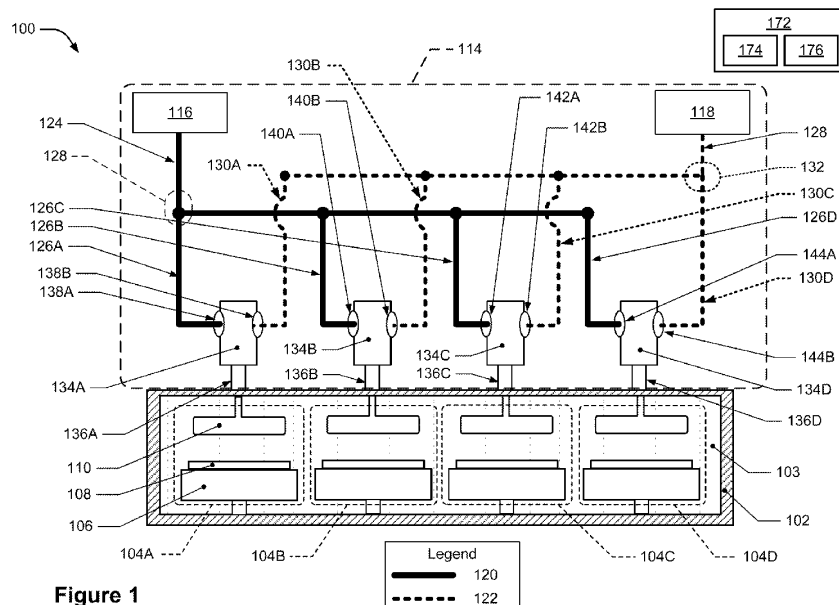


Figure 1

(57) **Abstract:** The present disclosure relates to a system for a semiconductor processing. The system includes a semiconductor processing chamber having a plurality of processing stations, a plurality of manifold trunks, a plurality of valves, and a plurality of fluid manifolds. Each manifold trunk includes an outlet, a common flowpath, a plurality of trunk inlets, a plurality of orifices, and a plurality of valve interfaces.

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